



PATENT

Atty. Dkt. No. AMAT/5083/CMP/CMP/RKK

IFW  
AF  
1765

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of:  
Wang, et al.

Serial No.: 09/842, 476

Confirmation No.: 7917

Filed: April 25, 2001

For: Chemical Mechanical Polishing  
Composition and Process

Group Art Unit: 1765

Examiner: Lynette Umez-Eronini

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Commissioner for Patents  
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Dear Sir:

## RESPONSE TO FINAL OFFICE ACTION DATED APRIL 14, 2004

In response to the Final Office Action dated April 14, 2004, having a shortened statutory period for response set to expire on July 14, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/5083/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 7 of this paper.